



Tool Make & Model

ASML TWINSCAN XT:1900Gi

Tool Configuration / Specifications

ASML XT 1900Gi 300mm litho tool

Software Version: 5.0

CIM: SECS, GEM

Process: Immersion Lithography

Factory Interface: SMIF

Options System:

- Agile
- 300mm FOUP
- Version 5.0 Immersion Hood
- ART OHT interface
- SMASH Alignment
- Baseline Focus
- Cymer XLA 360 Laser
- Reticle Library
- Aux Exhaust Unit

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Software Key Overview

GMD1

XT1900i		
Software Key	Software Key Value	
2 Sided IFM-beams for WS-X (expose)	Available for production	05-JUN-07
	Not available	
2 Sided IFM-beams for WS-X (measure)	Available for production	01-JUN-07
	Not available	
2D Barcode Reader	Absent	01-JUN-07
2D grid correction	Enabled	01-JUN-07
AA processing rack	MPCR processing rack	
	MPCR2 processing rack	01-JUN-07
ALE 1 Use	Calibration	01-JUN-07
AMCR configuration	No configuration specified	07-APR-10
APACE used in production.	APACE is disabled in production.	07-APR-10
AST offset usage during LOCO TIS	Disabled	30-JAN-15
Activate 2Dspg for long y-moves only. Protected	2Dspg for long y-moves only disabled	30-JAN-15
Activate ESO MAX speed Allowed. Protected	ESO MAX Speed Allowed Disabled	30-JAN-15
Activate Edge Speed Limiter. Protected	Edge Speed Limiter Disabled	
	Edge Speed Limiter Standard	25-OCT-12
Activation of the airknife during hovering	Airknife disabled during hovering in wet mode	25-OCT-12
	Airknife enabled during hovering in wet mode	
Active Pupil Aberration Correction Element type	APACE Absent	09-OCT-09
Active Pupil Aberration Correction lens Element	Metrology does not use any APACE	07-APR-10
Active wafer release for dry WS	False	01-JUN-07
Adjust LHV oscillation threshold of the green laser	Enable decreased green laser oscillation threshold	26-OCT-12
Air Gauge	Present	09-JAN-08
Air Gauge Improved Levelling	AGILE1	30-JAN-15
Alignment Camera Mirror	Absent	01-JUN-07
Alignment Sensor Type	Athena Narrow Marks OM	01-JUN-07

	Smash OM	
Alignment Settle Time	Basic	30-JAN-15
Alignment laser configuration	2 color laser	01-JUN-07
	4 color laser	
Allow L1L7 Type 1 Optimization	Absent	
	Present	03-AUG-07
Allow different Exp,TIS Align set	Absent	01-JUN-07
Allow even orders usage	Absent	01-JUN-07
	Present	
Allow wafer plane deviation check with Focus Monitoring	Disabled	
	Enabled	14-MAR-14
Angular sensitivity corrections of Spot Sensor on Chuck 1	Disabled	
	Enabled	15-APR-10
Angular sensitivity corrections of Spot Sensor on Chuck 2	Disabled	
	Enabled	15-APR-10
Application Specific Lens Heating Calibration & Verification	Present	07-APR-10
Application Type	Scanner Application	01-JUN-07
Apply clamping grid correction during wafer align	disabled;	
	enabled;	19-MAY-10
Assure System Snapshots	Assure System Snapshots not allowed	30-JAN-15
Ast offset correction in TIS LHFB/LOCO (Version 3)	Disabled	01-JUN-07
Athena Focus Improvements 1	Present	01-JUN-07
Athena Narrow Marks Twinscan	Present	01-JUN-07
Attenuator Mirror Type	Quartz Attenuator Mirror	15-APR-10
Attenuator Type	Variable	01-JUN-07
Automated DOE Exchanger	Present	01-JUN-07
Automated DOE Exchanger Architecture	16 slots	01-JUN-07
Automated Lens Heating Calibration	Disabled	
	Enabled	07-APR-10
Automated Reticle Transport System	Present	28-NOV-07
Automatic CUA	Absent	01-JUN-07

Automatic CUA exchanger architecture	Adjacent to the Rema objective	01-JUN-07
Automatic PCE exchanger	Present	01-JUN-07
Availability of WID readout functionality	WID readout functionality absent	11-FEB-19
Availability of chucks in the waferstage compartment.	Both chucks are present.	07-APR-10
Availability of inline WTQT functionality	Inline WTQT functionality disabled	11-FEB-19
Availability of the FlexWave module	FlexWave module not available	30-JAN-15
Avoid I1 or I2 mark on TIS plates	Disabled;	07-APR-10
Avoid Track INPUT/OUTPUT conflicts, Raise AS after APR	Avoid Track INPUT/OUTPUT conflicts disabled	16-JUL-08
	Avoid Track INPUT/OUTPUT conflicts enabled	
BA-XY Reticle preference: V1 or V2; default is V2	V1 BA-XY Reticle	30-JAN-15
BALE Type	Piezo Valves	01-JUN-07
	WS15G Valves	
Barcode Reader configuration at IRL.	Not configured. Update according to the BCR present at IRL.	
BaseLiner Optima WEC/REC Control	BaseLiner Optima WEC/REC application is disabled.	30-JAN-15
BaseLiner focus control.	BaseLiner-Focus application is enabled.	07-APR-10
BaseLiner focus high order intrafield	BaseLiner-Focus high order intrafield is disabled.	25-OCT-12
BaseLiner overlay control.	BaseLiner-Overlay application is enabled.	07-APR-10
Baseliner diffraction based focus stability control	Baseliner diffraction based focus stability control disabled	30-JAN-15
Beam Control	Closed loop	01-JUN-07
Beam Shaping Module	No Beam Shaping Module present	
Behavior of the FlexWave module	FlexWave not controllable	30-JAN-15
Bubble Extraction Seal Setting	Bes boost 2	26-OCT-12
CDC	Enabled	01-JUN-07
CT Miscellaneous Rack	Present	01-JUN-07
Capacitive z-height sensor type.	Extended Z sensor board	01-JUN-07
Carrier Handler Type	Mark II 300 Foup	01-JUN-07
	Mark III 300	
Center pole location in the machine	Center pole is located in the center	
	Center pole is shifted towards the measure area	25-OCT-12
Changed Short Stroke diff XY controller	Disabled	01-JUN-07
Choice of COWA1 vertical setpoint calculation	Wait for current wafer capture result for the calculation	10-SEP-17

Choice of avoidance routing.	Phase 2	01-JUN-07
Choice of horizontal stage align setpoint	Wait for vertical stage align result	30-JAN-15
Choice of wafer capture position	Perform wafer capture at SOSI scan-in position	10-SEP-17
Chuck 1 wafer size	300mm	01-JUN-07
Chuck 2 wafer size	300mm	01-JUN-07
Chuck Dedication	Enhanced	20-AUG-09
Circuit Dependent FEC	Present	01-JUN-07
Clean Air Configuration	Air Shower Type 7A low pressure	
	Others	01-JUN-07
Clean Air Temperature Control	Driver and ACC	01-JUN-07
Clean Air Temperature Performance level	Level 2	25-OCT-08
Closing disk type	SiC closing present	01-JUN-07
CoWa2 vertical setpoint	Use Global Wafer Wedge result as CoWa2 vertical setpoint	30-JAN-15
Combined stage alignment	Disabled	
	Enabled	07-APR-10
Communication with Air Control Cabinet	RS232 communication	24-AUG-10
Computational ASCAL	Commercial cASCAL option disabled	30-JAN-15
Configuration Identification CARM Stages Stack	No Configuration Specified.	30-JAN-15
Configuration id for reticle handling electronics	No configuration specified	30-JAN-15
Configuration identification for AMCR electronics	No configuration specified	30-JAN-15
Configuration identification for PCHR (Handlers) electronics	No configuration specified	30-JAN-15
Configuration identification for PCSR electronics	No configuration specified	30-JAN-15
Configuration identification for projection mechatronics	No Configuration Specified.	30-JAN-15
Configuration identification for projection software	No Configuration Specified.	30-JAN-15
Configuration identification of the accelerometers	Accelerometer configuration 1	30-JAN-15
Configuration identification reticle positioning electronics	No configuration specified	30-JAN-15
Configuration identification wafer positioning electronics	No configuration specified	30-JAN-15
Configuration identifier planar stage chuck 1 linear axis	No configuration specified	30-JAN-15
Configuration identifier planar stage chuck 1 long stroke	No configuration specified	30-JAN-15
Configuration identifier planar stage chuck 1 short stroke	No configuration specified	30-JAN-15
Configuration identifier planar stage chuck 2 linear axis	No configuration specified	30-JAN-15

Configuration identifier planar stage chuck 2 long stroke	No configuration specified	30-JAN-15
Configuration identifier planar stage chuck 2 short stroke	No configuration specified	30-JAN-15
Configuration of planar stage chuck 1 corner-cubes	No configuration specified	30-JAN-15
Configuration of planar stage chuck 2 corner-cubes	No configuration specified	30-JAN-15
Configuration of the In-Vacuum Robot Z-axis motor.	No configuration specified	30-JAN-15
Constrained fit	Disabled	01-JUN-07
Continuous clampable wafer table for dry WS	Absent	01-JUN-07
Control the APCAP miscapture recovery	The APCAP miscapture recovery is disabled	22-MAY-16
Controls parasitic stiffness type	Type 1, no spec selection	22-MAY-16
Corr. Per Exposure Lot reporting includes ADELSbcoverlay.	Include the ADELSbcoverlay intrafield contribution.	30-JAN-15
DOEs in lower disk ADE	Not Applicable	27-JUL-17
DOSEMAPPER	Present	01-JUN-07
DOSE_MAPPER_1	Present	01-JUN-07
DUV Lightsource Power Level	60.00 Watt	12-JUL-07
Data collection not covered by FOCUS and OVERLAY	Disabled	25-OCT-11
Dedicated Stage Alignment	Disabled	30-JAN-15
Delay ret move from RS during idle cond, m-act and CPDs	Delay reticle move requests from or to stage	30-JAN-15
Depolarizer type	no retarder but pce-depolarizer	07-APR-10
Depth of Focus enhancement with adjustable laser bandwidth	Laser bandwidth is not adjustable	07-APR-10
Derived Lens Type for common metrology software	07	
	91	30-JAN-15
Describes at what plane the BMU measures	Correct for BMU below DOE1 level	07-APR-10
Determination of NA ellipticity	Disabled	01-JUN-07
Diaphragm Limiter	Absent	01-JUN-07
Diff pressure correction for IFM beams	Absent	
	Present	01-JUN-07
Disable or enable the encryption of Recipes send to the Tool	Do not encrypt any recipes or layer files on Tool.	22-MAY-16
Docking wheels at WH unload	Absent	01-JUN-07
Dose Intensity Optimization	Disable Dose Intensity Optimization;	24-AUG-10
Dose System Performance Test for Lithoguide	Present	01-JUN-07
Dose evaluation functionality for UV systems	Dose Evaluation for UV systems disabled	27-JUL-17

DoseSystemPerformanceTest sequence	Test sequence 1	07-APR-10
Dosecontrol Hardware	DCB	01-JUN-07
Double TIS scan	Disabled	01-JUN-07
Dynamic Performance Calculation	Mark 2	01-JUN-07
E-chuck Flatness Qualification Test	Disabled	01-JUN-07
EDA Interface	Disabled	01-JUN-07
EDA Interface standard Freeze	Level I	
EDO	Disabled	24-AUG-10
EFESE	Absent	
	Present	20-AUG-09
ESC wait and repeat functionality	ESC wait and repeat functionality is not available	27-JUL-17
ESO Manual Override	ESO Manual Override Disabled	25-OCT-11
EUV Lightsource Architecture	Laser Produced Plasma	30-JAN-15
EUV sources	Pilot and following Source(s)	30-JAN-15
Editable M-action queues	Editable M-action queues disabled	07-APR-10
Electronics-box version of chuck 1	No version specified	30-JAN-15
Electronics-box version of chuck 2	No version specified	30-JAN-15
Enable ExpoFlex functionality	ExpoFlex is unavailable	30-JAN-15
Enable or disable SLIP / Intensity protection	SLIP / Intensity protection is disabled	04-DEC-15
Enable or disable image alignment fading correction	Disable image alignment fading correction	04-DEC-15
Enable the Maintenance Assistant	Disable Maintenance Assistant	
	Enable Maintenance Assistant	26-OCT-12
Enable the new fit algorithm, supporting BGRM for periodic scan types, when enabling this switch.	Disable the SMASH FFT fit algorithm for periodic scan types.	30-JAN-15
Enable to support SMASH XY mark types.	SMASH XY marks are not supported.	07-APR-10
Enable/Disable LoS2SS error FF on measure side	LoS2SS error FF settings according to MCs	30-JAN-15
Enables RA Multiple Scans	Disable RA Multiple Scans	30-JAN-15
Enables SA Multiple Scans	Disable SA Multiple Scans	30-JAN-15
Enables idle condition chuck swap	Wafer Stage Idle conditioning for immersion disabled	27-JUL-17
Enables system idle conditioning	System idle conditioning disabled	30-JAN-15
Energy Sensor	Star TechC	01-JUN-07

Energy sensor calibration type. Protected	Normal	30-JAN-15
Enhanced Exposure Overlay	Full	01-JUN-07
Enhanced Throughput Reticle Alignment	Extended	01-JUN-07
Enhanced exposures 1	Present	01-JUN-07
Enhancements in Reticle Monitor	no enhancements	31-OCT-07
Equipment Constants via SECS interface	Disabled	
	Enabled	03-AUG-07
Exchangeable Last Lens Element	Present	01-JUN-07
Exchangeable Pupil Lens Element	EPL Type INACTIVE	14-FEB-12
Exposure routing throughput optimization for KrF	Exposure routing throughput optimization for KrF is disabled	30-JAN-15
Extend IRIS maximum particles scanned to 50000.	Absent	
	Present	13-JUL-07
Extended LS areas	Enabled	03-AUG-07
Extended Lens Heating History (ELHH)	Enabled	07-APR-10
Extended Spot Sensor Matching	Present	01-JUN-07
Extended Zone Alignment	Disabled	30-JAN-15
Extended maximum for FILS Timeout.	Standard	13-DEC-10
Extended measurements after expose	Disabled	07-APR-10
Extended minimum for FILS Timeout.	Standard	13-DEC-10
Extreme Clean Humidified Air	Present	01-JUN-07
FOCAL Measurement for Lithoguide	Present	01-JUN-07
FSM Flexibility package	Disabled	01-JUN-07
Fast Avoidance Routing	Disabled	30-JAN-15
Fast VSA	Fast VSA is disabled	30-JAN-15
Fast Wobble	Disabled	
	Enabled	30-JAN-15
Field Dependent DOE Exclusion library	present	13-FEB-20
Field width optimised leveling	Disabled	03-AUG-07
Filtering of the SUSDC correction.	Filtered SUSDC correction is disabled.	30-JAN-15
FlexRay Control Rack Configuration	Absent	07-APR-10
FlexWave Mode for Production	NONE - FlexWave is not used for production	30-JAN-15

Flexible Productivity	Enhanced productivity mode disabled	04-DEC-15
Flexray illuminator	Flexray Absent	24-AUG-10
Focus Data Collection	Absent	01-JUN-07
Focus Improvement Package (OBSOLETE key).	OBSOLETE.	30-JAN-15
Focus Monitoring	Absent	
	Present	14-MAR-14
Functional use of Active Elements	BALE function as BALE	01-JUN-07
Gas Control Unit Type	Ultra High Flow (UHF)	01-JUN-07
Gas Facilities: Gas Supply Lens Manipulator	Gas supply lens manipulator hardware not present	30-JAN-15
Gas Facility / Airknife: Point Of Use Humidifier	No point of use humidifier hardware present.	30-JAN-15
Gridmapper	Enabled	20-AUG-09
Hardware configuration identification of wafer clamps	CF unit	30-JAN-15
Hardware configuration identification of wafer table clamp	CFC unit	30-JAN-15
Hardware configuration of LoS2BM actuator version	No configuration specified	30-JAN-15
High resolution System performance	Disabled	27-JUL-17
IFM Laser Configuration	AOM Recombo Laser	01-JUN-07
ILIAS Fast Zernike concatenation	ILIAS Fast Zernike concatenation disabled	30-JAN-15
ILIAS Functionality For Lithoguide	Present	01-JUN-07
ILIAS Pupil measurement performance node	ILIAS Pupil measurement performance node 17	
	ILIAS Pupil measurement performance node 19	30-JAN-15
ILIAS Sensor Location	Both	01-JUN-07
ILIAS Zernike measurement performance node	ILIAS Zernike measurement performance node 17	
	ILIAS Zernike measurement performance node 19	25-OCT-12
ILIAS lens setup	Absent	01-JUN-07
ILIAS number of supported Zernikes	ILIAS number of supported Zernikes 37	30-JAN-15
ILIAS sensor type chuck 1	Hyper NA MK3	
	Hyper NA MK5	25-OCT-12
ILIAS sensor type chuck 2	Hyper NA MK3	
	Hyper NA MK5	25-OCT-12
IRL barcode reader type	1D barcode reader is present at IRL	
ISIS Functionality For Lithoguide	Absent	01-JUN-07

Identification of ESC hardware variants Chuck1	No clamp hardware available	30-JAN-15
Identification of ESC hardware variants Chuck2	No clamp hardware available	30-JAN-15
Identification of Positioning Module Supply Box version	No configuration specified	30-JAN-15
Identification of SLR brakebox type	Type 1 brakebox hardware	30-JAN-15
Identification of SLR clamp voltage	No voltage used on SLR clamps	30-JAN-15
Identification of SUR brakebox type	Type 1 brakebox hardware	30-JAN-15
Identification of SUR clamp voltage	No voltage used on SUR clamps	30-JAN-15
Identification of VPA clamp voltage	No voltage used on VPA clamps	30-JAN-15
Ifm config at measure side.	8 axes	01-JUN-07
Illumination modes	All illumination modes	01-JUN-07
Illuminator Machine Safety Hardware	PTI board	07-APR-10
Illuminator Type	170	
	190	01-JUN-07
Illuminator platform	Aerial XP	01-JUN-07
Illuminator temperature sensors	No temperature sensors present	30-JAN-15
Image quality data path arch	Data path architecture A	07-APR-10
Imaging Control Rack Configuration	IMCR	01-JUN-07
Imaging Electronics Architecture	B Architecture	01-JUN-07
Imaging Fading Control	Lens set-up only	01-JUN-07
Imaging Generic Power Amplifier	Ten Axis Power Amplifier	01-JUN-07
Imaging performance package	Standard imaging performance settings for non-8xy	21-OCT-10
Immersion	Present	01-JUN-07
Immersion Hood Sub version	Sub-Version 1	25-OCT-12
Immersion Hood SubSub version	Not Applicable	30-JAN-15
Immersion Hood version	Version 4	
	Version 5	25-OCT-12
Immersion hood heater configuration	Four segmented heaters on top	25-OCT-12
	Internal single segmented heater	
Immersion style Final XY tools for Dry Systems	Disabled	30-JAN-15
Improved CDFEC/FWOL application on non-yielding fields.	Enabled	30-JAN-15
Improved Contrast Control	Absent	01-JUN-07

	Present	
Improved Edge Field Leveling	Disabled	
	Enabled	30-AUG-19
Improved FSM algorithm. Part of FIP-1 commercial package.	Disabled	30-JAN-15
Improved Maintenance action scheduling.	Disabled	01-JUN-07
Improved Reticle Control	Basic TOP-RC behavior	07-OCT-18
Improved robustness DPCM fit	Enable improved robustness DPCM fit	30-JAN-15
Improved wafer reject mode	Disabled	
	Enabled	26-OCT-12
Improvements for reticle handling	Disabled	01-JUN-07
In situ Wafer Table Stone Cleaning	Absent	
	Present	30-JAN-15
In situ Wafer Table Stone Cleaning Hardware Version	Stone 1	
	Stone 2	30-JAN-15
Indicate which leveling spec shall be used.	The leveling spec is unknown.	22-MAY-16
Indicates the method used to detect a wafer on VPA	Detect wafer using the Vacuum Prealigner electrostat. clamps	30-JAN-15
Indicates whether the SFPM model is enabled	The SFPM model is disabled	30-JAN-15
Indicates which overlay spec is used	The overlay spec is set to SPEC_1	08-FEB-18
Indication what kind of AM controller hardware is present	DICR	01-JUN-07
	SUCR	
Inlet restriction for clean air	Inlet restriction at right side	01-JUN-07
Insert a delay time before starting a Lot (lens heating).	Disabled	07-APR-10
Integrated Reticle Inspection System	PPD1 with IRIS1 functionality.	
	PPD2 with IRIS5um functionality.	13-JUL-07
Integrated Reticle Inspection System Configuration.	Disable creation of OSIRIS viewable files.	
	Enable creation of OSIRIS viewable files for PPD2 systems.	13-JUL-07
Integrated Reticle Library	IRL with original functionality	20-AUG-09
Intensity Calibration Per DOE	Disabled	
	Enabled	20-AUG-09
Intensity Calibration Type	Type 1	
Interferometer Electronics	lfsr	01-JUN-07

Interferometer axis version at exposure	3 plus 1 axis	01-JUN-07
Interfield Scan Up Scan Down focus correction	SUSD enabled model type 1	19-MAY-10
	SUSD enabled model type 2	
Intrafield Higher Order Process Corrections	Disabled	25-OCT-12
	Enabled	
Intrafield Higher Order Process Corrections Per Exposure	Intrafield HOPC per exposure is Disabled	30-JAN-15
Intrafield Wafer Alignment	Disabled	20-AUG-09
Iris feature Scan	Absent	
	Present	13-JUL-07
Is NA accuracy measurement allowed?	Disabled	01-JUN-07
Is the UPS Ethernet connected to the Twinscan.	UPS is not connected to the Twinscan.	30-JAN-15
Is this a machine with a safety PLC.	Safety PLC is not available in the Twinscan.	30-JAN-15
LAR event log pollution reduction	Enable LAR event log pollution reduction	20-DEC-13
LCI WaitWatcher plug-in	Absent	01-JUN-07
LCW Circuit set-up	Pressure Version 1	01-JUN-07
LEC Rack in Electronic Architecture	Absent	01-JUN-07
LS focus node	LS focus node 5	01-JUN-07
LS spot coverage	Absent	01-JUN-07
LS_CPU_CONFIG	1 CPU available	01-JUN-07
	2 CPU's available	
LS_PEMM_CONFIG	Absent	01-JUN-07
	Present	
LVT modeling version.	LVT model version 1 is enabled.	30-JAN-15
Laminar Bottom Hood	Absent	01-JUN-07
Large Range Leveling	Disabled	04-DEC-15
Laser Gas Life eXtension	Disable Laser Gas Life eXtension;	25-OCT-08
Laser capability for retrieving High Bandwidth Data	Laser does not provide Bandwidth Data	30-JAN-15
Layout Usage TIS Sensor	DUV TIS Sensor	30-JAN-15
Layout Version Number TIS Fiducial	TIS Fiducial Layout Version 1	30-JAN-15
Layout Version Number TIS Plate 1 on Chuck 1	TIS Plate 1 Layout Version 5	
	TIS Plate 1 Layout Version 5.5	25-OCT-12

Layout Version Number TIS Plate 1 on Chuck 2	TIS Plate 1 Layout Version 5	
	TIS Plate 1 Layout Version 5.5	25-OCT-12
Layout Version Number TIS Plate 2 on Chuck 1	TIS Plate 2 Layout Version 5	
	TIS Plate 2 Layout Version 5.5	25-OCT-12
Layout Version Number TIS Plate 2 on Chuck 2	TIS Plate 2 Layout Version 5	
	TIS Plate 2 Layout Version 5.5	25-OCT-12
Layout dependent corrections.	Layout dependent effects are not corrected.	11-FEB-19
Lens Active Vibration Absorber	Absent	30-JAN-15
Lens Circuit Water Flow	High Immersion	01-JUN-07
Lens Heating Feedback	Absent	01-JUN-07
Lens OverPressure Compensation	OverPressure Compensation Disabled	21-OCT-10
Lens Top Tool Connection	Lens Top Tool can not be mounted on top of the Lens	01-JUN-07
Lens Type	07	
	91	01-JUN-07
Level Sensor Processing Rack	MPCR	01-JUN-07
Leveling Verification Test for Lithoguide	Present	01-JUN-07
Levelling throughput improvement on measure side	Levelling throughput package A	01-JUN-07
	No levelling throughput package	
Light source selection, for FIR laser	Light source selection undefined	08-FEB-18
Light source selection, for NIR laser	Light source selection undefined	08-FEB-18
Light source selection, for green laser	Light source selection undefined	08-FEB-18
Light source selection, for red laser	Light source selection undefined	08-FEB-18
Light-source Architecture	Laser	01-JUN-07
Light-source Type	Cymer Laser: XLA 360 60W, 10 mJ, 6.0kHz	
	GPI Laser: GT61A4 60W, 10 mJ, 6.0kHz	19-JUN-07
Light-source Wave-length	193nm	01-JUN-07
Liquid Particle Counter Unit	No Liquid Particle Counter Unit installed	25-OCT-08
Lithoguide Imaging Recipes	Absent	
	Present	03-AUG-07
LoCo C2C drift correction	Disabled	27-JUL-17
Load Robot Internal Docking	WH LR Without Damping	07-APR-10

Load Robot Wrist Assy Type	WH LR Wrist Long Tension Rod	07-APR-10
Loadport barcode reader type	Original barcode reader at the loadports	30-JAN-15
Location of PARIS sensor on chuck 1	No PARIS sensor on chuck 1	30-JAN-15
Location of PARIS sensor on chuck 2	No PARIS sensor on chuck 2	30-JAN-15
Log missed translations	Disabled	01-JUN-07
Long Stroke Sliding Mode Controller	Disabled	30-JAN-15
Lot Alignment Report Encryption	Unencrypted	01-JUN-07
Lot Correction Sequence	Type D	
	Type E	07-NOV-12
Lot Overhead Reduction	LOR2	01-JUN-07
Lot Report Data Category	Enhanced Diagnostics	01-JUN-07
MALE used in production.	MALE is disabled in production.	23-MAY-10
MDL Viewer	Site View	01-JUN-07
Machine Architecture	XT Machine Architecture	01-JUN-07
Machine Location	Customer Site	31-OCT-07
Machine Performance level	None	04-DEC-15
Machine Specification	F Specification	
	G Specification	01-JUN-07
Machine Type	1700	
	1900	01-JUN-07
Max alignment speed	Setting 2	01-JUN-07
Maximum Reticle ID Length	24 Characters	03-AUG-07
Maximum numerical aperture (NA) allowed in Lot Production	level 0	30-JAN-15
Measure and model strategy for vertical stage align	VSA and advanced XVSA	
	iVSA	25-OCT-12
Method for alignment of the laser beam	Align beam by optimizing pupil telecentricity params: LUBB	07-APR-10
Metroframe Circuit Water Cabinet	Absent	01-JUN-07
Metroframe Temperature Performance level	Level 1	07-APR-10
Metroframe type	TYPE_A	01-JUN-07
Metrology overlay setup method	Metrology overlay setup calibration to nominal	30-JAN-15
Modelling for MAXYS	Absent	01-JUN-07

Motor Circuit Water Flow	High Immersion	01-JUN-07
Move profile parameter configuration chuck 1	Not specified	30-JAN-15
Move profile parameter configuration chuck 2	Not specified	30-JAN-15
Multi Functional Exchangeable Lens Element	Projection lens has no MF-EPL	07-APR-10
Multifunction Active Lens Element	0	01-JUN-07
Multifunctional Active Elements	0	01-JUN-07
Multilingual UI	Absent	01-JUN-07
Multiple wafers on output path configuration	Only one wafer at a time on the output path possible	27-JUL-17
NA Control Architecture	NA3 Half Bridge	01-JUN-07
NA Control Type	170	
	190	01-JUN-07
NA1 motor type	None	01-JUN-07
NXE Arch. revision	no revision	30-JAN-15
NXT Arch. revision	no revision	07-APR-10
Net lot overhead optimization for exposure sequence	No optimization	04-DEC-15
Nitrogen Purge Utility Control	Absent	01-JUN-07
Nitrogen purging of Reticle Stage	RS is not purged	01-JUN-07
Number of Active Elements	2	01-JUN-07
Number of Active Lens Elements	0	01-JUN-07
Number of Active Manipulator Elements	0	01-JUN-07
Number of Bi-directional Active Lens Elements	2	01-JUN-07
Number of EXLE elements	0	
	1	01-JUN-07
Number of Half Dome Mirrors	2	01-JUN-07
Number of Lens NEXZ Manipulators	6	01-JUN-07
Number of Lens Z Manipulators Using Camdisk	0	01-JUN-07
Number of Motion Controllers	5 Motion Controllers present	01-JUN-07
Number of RMCS clients	No clients	01-JUN-07
Number of Rxm	6	01-JUN-07
Number of Rym	6	01-JUN-07
Number of Semi-Active X-Y Lens Manipulators	6	01-JUN-07

Number of Z Lens Manipulators	6	01-JUN-07
Number of active mirror elements used in NXE POB	Zero active mirror elements	30-JAN-15
Number of bending points (mirrors).	Not applicable.	30-JAN-15
Number of manipulable ELLE axes	5	
	6	01-JUN-07
Number of pre-amps available per Z-manipulator	0	01-JUN-07
Number of supported fast Zernikes	ILIAS number of supported Zernikes 25	30-JAN-15
OADB Improved Dynamic Range	Enabled	01-JUN-07
OASIS	OASIS absent	30-JAN-15
OIU display hardware	OIU display is implemented by a Sun Workstation	30-JAN-15
Off-axis slit	Projection lens has an off-axis slit.	01-JUN-07
Online Lamp Peak	Disable Online Lamp Peak;	24-AUG-10
Option to apply the usage of HO marks in StageAlign	Use XPA marks in StageAlign.	07-APR-10
Overlay Data Collection	Overlay Data Collection disabled.	07-APR-10
Overlay Node	Level 0	01-JUN-07
Overlay Node for Boost Mode Lot's	Level 53	07-DEC-17
PCE Location	pce in APEX	07-APR-10
PDGC correction subrecipe deletion	Enable deletion of ASML created PDGCCorr subrecipes	
PDOC correction subrecipe deletion	Enable deletion of ASML created PDOCCorr subrecipes	
PDOC quality indicator check	PDOC quality indicator functionality is absent	27-JUL-17
PED control mode	Absent	01-JUN-07
PEP High SLIP	PEP High SLIP is disabled	14-DEC-10
PEP Image Streaming	Present	01-JUN-07
PEP-ADC Intensity	Disable PEP-ADC Intensity;	24-AUG-10
POB Type	31	30-JAN-15
POB temperature sensors	No temperature sensor present	30-JAN-15
PSE Location	pse in PSER	07-APR-10
PSE type	XY polarization	07-APR-10
PSE-type of PSE located in ROE (Asymmetrical or Symmetrical)	Not Applicable	07-DEC-17
PUPICOM	Present	01-JUN-07
PUPICOM Architecture	Multi Spoke	01-JUN-07

PUPIL Measurement For Lithoguide	Present	01-JUN-07
PUPILIAS matching in terms of sigma measurement	Match ILIAS MK5 to MK4	25-OCT-12
	No matching	
PVP for disabling the laser burst interaction functionality	Enabled	30-JAN-15
Parameter indicates how long overlay data will be stored.	Short retention period.	07-APR-10
Particle Extraction Mass Flow Meter	Absent	07-APR-10
Patch strategy	Patchlevel	01-JUN-07
Pattern Matcher	Absent	24-AUG-10
Pattern Matcher Full Chip	Absent	24-AUG-10
Performance Enhancement Package	None	01-JUN-07
Physical location of OIU.	Not applicable.	30-JAN-15
Piezo Active Lens Mounts	Analog	
	Digital MK-1	01-JUN-07
Point-to-Point LS Machine Matching	Disabled	01-JUN-07
Polarization	Present	01-JUN-07
Polarization Shaping Element Retractor	PSER hardware installed in the machine	01-JUN-07
Polarized illumination amorph DOE.	Only unpolarized illumination.	01-JUN-07
Position Control Motion Control rack	MPCR	01-JUN-07
Position Control Power Rack Configuration	TYPE_4: Stages Power Rack upto F-spec	
	TYPE_5: Stages Power Rack upto G-spec	01-JUN-07
Position of Spot Sensor on Chuck 1	Spot Sensor Position on Chuck 1 layout 3	01-JUN-07
Position of Spot Sensor on Chuck 2	Spot Sensor Position on Chuck 2 layout 3	01-JUN-07
Possible triggers for disk cleaning	M-action can trigger disk cleaning	07-OCT-18
Power rack configuration	Phase_1/XTIII electronics (reduced safety settings)	07-APR-10
Power supply type used for the wafer table BES heater.	Not applicable	07-APR-10
Pressure update rate for fringelength correction	Pressure update rate 2 or 4 Hz	01-JUN-07
	Pressure update rate 40 Hz	
Process Dependent Gain Correction	Present	21-DEC-07
Projection GPA Configuration Version	Version 2	01-JUN-07
Provides improved TIS CPD when enabled.	Provides improved TIS CPD for diagnostics only	04-DEC-15
Proximity Matching	Present	01-JUN-07

Pupil TIS angular sensitivity calibration and correction	TIS Pupil Measurement will not be improved	01-JUN-07
Pupil forming optics	Zoom, axicon and DOE	07-APR-10
Pupil measurements with ILIAS	Present	01-JUN-07
Pupil qualification method	Centre of gravity method	
	Geometric centre method	31-OCT-07
Purge Hoods configuration	Extremely Clean Dry Air only	01-JUN-07
REMA architecture	XTREMA	01-JUN-07
RS Object Field	Shifted 17x0	
	Shifted 19x0	01-JUN-07
RSC small NA correction.	RSC small NA correction is OFF.	30-JAN-15
Rapid prototyping using Python to control the machine.	Disable rapid prototyping.	07-APR-10
ReMa mark	Mark1	
	Mark2	01-SEP-17
Readout location of Pneumatic Facility Unit sensors	CT sensor board (CTS)	01-JUN-07
Recipe Creator	Absent	01-JUN-07
Reduce RS preptime for ILIAS scans.	Use default ILIAS preptime	04-DEC-15
Reduce wafer-load-offset tolerance of centring unit to 25 um	Standard	14-DEC-10
Reduced capture range for TIS scans	Disable reduced range TIS scan scenarios	
	Enable reduced range TIS scan scenarios	19-MAY-10
Relative direction of ws to rs on the X axis	Same	01-JUN-07
Reorder Lot Service	Present	06-DEC-07
Report if a Recipe was modified by remote Host or Operator.	Do not report how Recipe was changed.	22-MAY-16
Reporting of K9/K10 coefficients from reticle alignment	RA_K9_K10_DATA_COLLECTION is Disabled	07-OCT-18
Reticle Align High Precision	Absent	
	Present	20-AUG-09
Reticle Balance Mass 1 amp.	450V20A: PAAC AT-pepD	
	550V25A: PAAC XT rev3	01-JUN-07
Reticle Balance Mass 2 amp.	450V20A: PAAC AT-pepD	
	550V25A: PAAC XT rev3	01-JUN-07
Reticle Carrier Location	Left	01-JUN-07
Reticle Carrier Tag Reader	Present	18-JUL-07

Reticle Handler Machine Architecture	Reticle Handler is designed to handle reticles in air.	07-APR-10
Reticle Handler type	RH Mark IV	01-JUN-07
Reticle Heating Control	Reticle Heating Control is disabled	13-MAR-11
Reticle Heating Control acceptance test: zero layer reticle	RHC not supported	
Reticle Level Polarization Sensor	Present	01-JUN-07
Reticle Size	6 inch	01-JUN-07
Reticle Stage Chuck Type	TYPE_4: MGC_CLT, Glued LS, Magn. GC, ENC	
	TYPE_6: Two part chuck	14-FEB-12
Reticle Stage Lenscooler Box	Lenscooler Box with anti-aliasing Filter	01-JUN-07
Reticle Stage Long Stroke Config	TYPE_5:CoFe_18 motor,SIOB contr.,int. vacuum supply,magn. GC	
	TYPE_6:CoFe_18+magn.cooling,SIOB,int. vacuum supply,magn. GC	07-APR-10
Reticle Stage Long Stroke Motor Type	Cobalt Ferro 18 teeth	01-JUN-07
Reticle Stage Long Stroke Y11 amp.	450V20A: PAAC AT-pepD	
	550V25A: PAAC XT rev3	01-JUN-07
Reticle Stage Long Stroke Y12 amp.	450V20A: PAAC AT-pepD	
	550V25A: PAAC XT rev3	01-JUN-07
Reticle Stage Long Stroke Y13 amp.	Don't care	07-APR-10
Reticle Stage Long Stroke Y21 amp.	450V20A: PAAC AT-pepD	
	550V25A: PAAC XT rev3	01-JUN-07
Reticle Stage Long Stroke Y22 amp.	450V20A: PAAC AT-pepD	
	550V25A: PAAC XT rev3	01-JUN-07
Reticle Stage Long Stroke Y23 amp.	Don't care	07-APR-10
Reticle Stage Measurement System on Scan	Heidenhain Encoders	01-JUN-07
Reticle Stage Short Stroke X amp.	PADC 100V/18A	
	PADC 52V/6A	01-JUN-07
Reticle Stage Short Stroke Y11 amp.	PADC 100V/18A	
	PADC 130V/24A	01-JUN-07
Reticle Stage Short Stroke Y12 amp.	PADC 100V/18A	
	PADC 130V/24A	01-JUN-07
Reticle Stage Short Stroke Y21 amp.	PADC 100V/18A	
	PADC 130V/24A	01-JUN-07

Reticle Stage Short Stroke Y22 amp.	PADC 100V/18A	
	PADC 130V/24A	01-JUN-07
Reticle Stage Short Stroke Z1 amp.	PADC 100V/18A	
	PADC 52V/6A	01-JUN-07
Reticle Stage Short Stroke Z2 amp.	PADC 100V/18A	
	PADC 52V/6A	01-JUN-07
Reticle Stage Short Stroke Z3 amp.	PADC 100V/18A	
	PADC 52V/6A	01-JUN-07
Reticle Stage Short Stroke Z4 amp.	Don't care	07-APR-10
Reticle Stage purged mini environment	Present	01-JUN-07
Reticle Streaming 3	Reticle Streaming 3 Disabled	22-MAY-16
Reticle Temperature Sensor	RTS hardware is absent.	13-MAR-11
Reticle align capture	Always capture the reticle	07-APR-10
Reticle alignment scenarios	XT reticle align scenarios	07-APR-10
Reticle exchange type	Retex option: E	01-JUN-07
Reticle load protection for too wide/wrongly placed pellicle	Disabled	07-APR-10
Reticle shape correction	Enabled	01-JUN-07
Reticle stage parking	Disabled	30-JAN-15
Reticle streaming	Disabled	31-OCT-07
Reticle streaming II	Disabled	07-APR-10
Reticle streaming lite	Disabled	25-OCT-08
Robot Network Type	TYPE_1: Compensation filters are enabled	30-JAN-15
Robot position adjustment	DISABLED	13-FEB-20
SAMOS Stray Light Test For Lithoguide	Present	01-JUN-07
SASO robustness and fiber connectivity	Enable SASO robustness	26-OCT-12
SDM test on machines without SAXY elements	Disabled	14-DEC-10
SECS overlay corrections per exposure	Not allowed	07-OCT-18
SMASH Reuse Capture Information in Stage Alignment	Coarse capture scans are done on all stage alignment marks.	07-APR-10
SPM Dual Speed Data Delay	Absent	30-JAN-15
SPM WS Optimized Sampling	Disable optimized phase capturing	30-JAN-15
SPM WS Optimized Sampling TOP4	Disable optimized phase capturing	30-JAN-15

SPM reference axis at measure side (XT ARA)	No reference axis at measure side available	07-APR-10
SPM temp correction for lens axis	Disabled	20-AUG-09
Save throughput data to the disk	Disabled	
	Enabled	15-JUN-16
Scaling of Lot Correction field effects	Scaling of Lot Correction functionality is absent	04-DEC-15
Scan Direction Matching	Disable Scan direction matching	30-JAN-15
Scanner Control Host hardware type VP item	This TWINSCAN has a SUN Fire 240 as SCH	
	This TWINSCAN has a SUN Netra 240 as SCH	04-DEC-15
Scanning Energy Sensor Calibration	Scanning Energy Sensor Calibration	01-JUN-07
Select Reticle Puffing Availability	Reticle Puff Not Available	04-DEC-15
Set PUPICOM use	N_A	07-APR-10
Set UNICOM use	N_A	07-APR-10
Set new TOPRC MPM model	Use New Mechanical Prediction Model (2) for TOP-RC	30-JAN-15
Settle time reduction to improve the throughput	Default settle times	07-APR-10
Setup sensor board version	Setup SSD version LSDB	01-JUN-07
Shot Data Collection	Absent	01-JUN-07
Sigma Blade Exchanger	SBE absent	30-JAN-15
Single set of MCs for normal and Gridmapper expose scans.	mapping enabled;	30-JAN-15
Skip LS spots on TIS gratings for iVSA	Disabled	07-APR-10
Smooth Field Uniformity	Absent	01-JUN-07
Specifies chuck1 config	Immersion mark 3	01-JUN-07
Specifies chuck1 layout relev. for Immersion	TYPE_2:t.b.d.	01-JUN-07
Specifies chuck1 version	Version 2	01-JUN-07
Specifies chuck2 config	Immersion mark 3	01-JUN-07
Specifies chuck2 layout relev. for Immersion	TYPE_2:t.b.d.	01-JUN-07
Specifies chuck2 version	Version 2	01-JUN-07
Specifies which mark types are supported	ASML marks and custom marks	
	ASML marks only	16-JUL-08
Spot Sensor Chuck 1	VLOC	01-JUN-07
Spot Sensor Chuck 2	VLOC	01-JUN-07
Spot Sensor Reticle Stage	Present	01-JUN-07

Spotsensor chuck 1 surface coating	SiO2	06-NOV-12
Spotsensor chuck 2 surface coating	Bilatal	
	SiO2	06-NOV-12
Stage Alignment Filter	Absent	01-JUN-07
Stage Alignment Phases	Coarse and Fine stage alignment	25-OCT-12
	Fine stage alignment	
Stage align just before FIWA	Disabled	07-APR-10
Stages Sample Rate	5.0 kHz	01-JUN-07
Stages servo performance	Default servo performance	30-JAN-15
Stand-alone Workstation	False	01-JUN-07
Stressless wafer load for WS	Version 0	07-APR-10
Striping correction ILIAS sensor	Disabled	
	Enabled	07-NOV-12
Swap bridge 1 type	No swap bridge available	30-JAN-15
Swap bridge 2 type	No swap bridge available	30-JAN-15
Switch INFORMPRO2 Data Package reporting	InformPro2 is unavailable	07-OCT-18
Symmetrical Reticle Alignment	Enabled	01-JUN-07
THFFC FDE model lens dependent	Disabled	
	Enabled	01-JUN-07
TIS Power switching	Disabled	24-AUG-10
TIS diffuser	TIS diffuser absent	
	TIS diffuser present	01-JUN-07
TIS overlay and TPT node	TIS Overlay and Throughput Performance Node 17	
	TIS Overlay and Throughput Performance Node 19A	25-OCT-12
TIS plate deformation correction	Enabled	01-JUN-07
TIS plate usage in reticle align	RA always measures TIS1 and TIS2	07-APR-10
TIS plate usage in stage align	SA always measures TIS1 and TIS2	07-APR-10
TIS trigger mechanism	Use internal trigger mechanism	07-APR-10
TIS_ITOP	Disabled	
	Enabled	19-MAY-10
TOP HD	Present	01-JUN-07

Test Table	Absent	01-JUN-07
Test Table Z Axis	Worm Wheel	01-JUN-07
Test table architecture	Aerial XP	01-JUN-07
The cpu for 2DM software.	Absent	07-APR-10
The exposure field size to be used during the TPT test	Narrow Field size	30-JAN-15
The version indicates who implements the PFNI dose sequence	Metrology implements the PFNI dose sequence	11-FEB-19
To enable large range leveling improved PDGC calibration.	Improved large range PDGC disabled	27-JUL-17
To enable the closing wafer refresh functionality	Disabled	21-OCT-10
To indicate which 2D clamping spec shall be used.	The 2D clamping spec is unknown.	27-JUL-17
To indicate which 2D exposure spec shall be used.	The 2D exposure spec is unknown.	27-JUL-17
To indicate which FQ spec shall be used	The fq spec is disabled	27-JUL-17
To indicate which SDM spec shall be used.	The SDM spec is unknown.	27-JUL-17
To indicate which data delay spec shall be used.	The data delay spec is unknown.	27-JUL-17
To indicate which distortion spec shall be used.	The overlay spec is unknown.	22-MAY-16
To indicate which final xy spec shall be used.	The final xy spec is unknown.	27-JUL-17
To indicate which fine SDM spec shall be used.	The fine SDM spec is unknown.	27-JUL-17
To indicate which focal spec shall be used.	The focal spec is unknown.	27-JUL-17
To indicate which overlay spec shall be used.	The overlay spec is unknown.	22-MAY-16
To indicate which repeatability spec shall be used.	The overlay spec is unknown.	22-MAY-16
To switch OFF D2x and D2y corrections for LoCoE and 860lens	D2x and D2y corrections for LOCO E and 860 lens are OFF	30-JAN-15
To switch ON usage of multiple BA-XY reticle types, namely V1 or V2	BA-XY reticle type is V1	30-JAN-15
Track Pre-warning signal (APR)	APR disabled	26-OCT-12
	APR enabled	
Turns on second waferstage host in atca rack	WS2 host is absent, and CSGR must not try to boot it	30-JAN-15
Twinscan GUI display location	Twinscan is displayed at the OIU display	30-JAN-15
Twinscan autostart	Twinscan autostart is enabled	30-JAN-15
Type of 1st general purpose amp	TAPA	07-APR-10
Type of 5th general purpose amp	TAPA	07-APR-10
Type of Air Gauge	TYPE_1: Initial version	26-OCT-12
Type of Clamp Flow Unit installed for Wafer Stage	Clamp Flow Unit version installed is irrelevant	
Type of E-pin tips installed for Wafer Stage	Stiff E-pin tips	

Type of LS capture	Stepping	30-JAN-15
Type of MDRC used.	Not applicable.	30-JAN-15
Type of NEXZ actuator	NEXZ with 885nm range (NO3)	21-OCT-10
Type of PARIS sensor on chuck 1	No PARIS sensor on chuck 1	30-JAN-15
Type of PARIS sensor on chuck 2	No PARIS sensor on chuck 2	30-JAN-15
Type of e-pins calibration for Wafer Stage	1DOF (z only)	25-OCT-12
	Not applicable	
Type of immersion hood for immersion	Actuator Fixed Height	01-JUN-07
Type of inline cleaning cabinet	ILCC absent	07-APR-10
Type of level sensor gratings.	30um pitch grating for 16um LS Period	04-DEC-15
Type of measurement carried out as SFPM measurement	The SFPM measurement is disabled	07-APR-10
Type of projection multiplexer board	MUX type LAMB	01-JUN-07
Type of wafertable on chuck 1 for immersion machine	SiSiC version 4	
	SiSiC version 5	26-OCT-12
Type of wafertable on chuck 2 for immersion machine	SiSiC version 4	
	SiSiC version 5	26-OCT-12
UNICOM	Present	01-JUN-07
UNICOM Architecture	58 Motors	01-JUN-07
UPW Unit	Type A or type B UPW Unit installed	
	Type C UPW Unit installed	25-OCT-12
UV Shutter version	UV Shutter version 1	01-JUN-07
Ultra Pure Water Cabinet (UPWC) version	NO UPWC installed	30-JAN-15
Ultra Pure Water flow controller (WICC)	Entegris NT Flow Controller	01-JUN-07
Unicom move check	Unicom move check enabled	10-SEP-17
Uniformity Improvement Package	Present	01-JUN-07
Universal Prealignment	Disabled	01-JUN-07
	Enabled	
Unload Robot Wrist Assy Type	WH UR Wrist Long Tension Rod	07-APR-10
Unprepare fully preprocessed lot for M-actions	Disabled	
Usage of Energy Sensor data by TIS	Enabled	01-JUN-07
Usage of wavelength data by TIS	Enabled	01-JUN-07

Use Ryx or Ryz for the x Abbe correction	Not applicable	
	Use Ryx for the x Abbe correction	25-OCT-12
Use Sigma Calibration	apply Sigma Calibration	01-JUN-07
Use Sigma WIP Preserving Offsets	no Sigma WIP Preserving Offsets	01-JUN-07
Use TIS1-TIS2 Reticle Alignment scenario for K-spec	TIS1-TIS2 Reticle Alignment scenario for K-spec is ENABLED	30-JAN-15
Use a servo setting set	Default servo setting	30-JAN-15
Use improved setpoint calculations for shifted images	Improved setpoint calculations are ENABLED	30-JAN-15
Use the old at4.0.3 SPE sequence (ASF)	Do not overrule the SPE sequence	24-AUG-10
Use validity ranges around UIP data when Enabled.	Use exact matching for UIP data	01-JUN-07
Version of RS/WS IO library	Version 1	
	Version 2	01-JUN-07
Version of the Air Control Cabinet (ACC)	ACC MK 1 to 4	24-AUG-10
WES 2000M hardware presence	Absent	
	Present	25-OCT-12
WH Dock spring leaf cam typ	Hard	30-JAN-15
	Soft	
WH Robot Power Amplifier	CPM 20	01-JUN-07
WH temperature conditioning type	Slow performance type used for XTIII and below.	07-APR-10
WS 14db controller.	WS 14db controller DISABLED.	30-JAN-15
WS Balance Mass	Stainless Steel	01-JUN-07
WS Immersion Hood Only Testrig	Absent	01-JUN-07
WS Immersion throughput package	Tiger mode chuck swap closing disc exchange	07-APR-10
WS Immersion wafer table thermal control package	Single BES heater and cold-end wafer table heater	
	Six segmented BES heater and cold-end wafer table heater	26-OCT-12
WS Wafer Align Scans	Default	27-JUL-17
WS Zeroing using Absolute Phase Capturing	Off	30-JAN-15
WS improved step/scan behaviour.	Standard step/scan behaviour	30-JAN-15
WS prediction of wafer exchange timing	Default	08-FEB-18
WS servo error is fed to RS for better combined performance	disabled	10-SEP-17
WVAC Unit	Type A WVAC Unit installed	
	Type B WVAC Unit installed	30-JAN-15

Wafer Carrier Location	Left	01-JUN-07
Wafer Handler Pre-aligner Type	Pre-aligner with air-bearing table	
Wafer Handler Productivity	Wafer Handler Productivity Level 1	01-JUN-07
Wafer Handler wrt BF Shifted in Z	Not Shifted	01-JUN-07
Wafer Handling Docking Plate	WH Docking Plate Extra Low Height	07-APR-10
Wafer Handling Drying Unit	WH Drying Unit Absent	07-APR-10
Wafer Handling Load Robot Type	Scara Arm, 40 mm Z stroke	01-JUN-07
Wafer Handling Pneumatics	Standard	01-JUN-07
Wafer Handling Store Unit Type	WH Store Unit 3 Slotted	07-APR-10
Wafer Handling TSU	WH TSU Heater Absent	07-APR-10
Wafer Handling Track Input	WH Wafer Track Input Via PU	07-APR-10
Wafer Handling Unload Robot Type	Scara Arm, 40 mm Z stroke	01-JUN-07
Wafer Id Reader	Absent	01-JUN-07
Wafer Mark Sensor	Absent	01-JUN-07
	Present	
Wafer Size	300mm	01-JUN-07
Wafer Stage Balance Mass 11 amp.	Don't care	01-JUN-07
Wafer Stage Balance Mass 12 amp.	Don't care	01-JUN-07
Wafer Stage Balance Mass 21 amp.	Don't care	01-JUN-07
Wafer Stage Balance Mass 22 amp.	Don't care	01-JUN-07
Wafer Stage Coarse Wafer Align Improvement	None	10-SEP-17
Wafer Stage Configuration	Wafer Stage type 3 configuration	
	Wafer Stage type 4 configuration	01-JUN-07
Wafer Stage Dedicated Hardware Configuration	None	21-OCT-10
Wafer Stage Expose Scan Strategy	Default	27-JUL-17
Wafer Stage Fast Stiff X Move Electronics	Present	01-JUN-07
Wafer Stage Long Stroke E CS amp.	450V20A: PAAC AT-pepD	
	550V25A: PAAC XT rev3	01-JUN-07
Wafer Stage Long Stroke E X amp.	450V20A: PAAC AT-pepD	
	550V25A: PAAC XT rev3	01-JUN-07
Wafer Stage Long Stroke E Y1 amp.	450V20A: PAAC AT-pepD	

	550V25A: PAAC XT rev3	01-JUN-07
Wafer Stage Long Stroke E Y2 amp.	450V20A: PAAC AT-pepD	
	550V25A: PAAC XT rev3	01-JUN-07
Wafer Stage Long Stroke M CS amp.	450V20A: PAAC AT-pepD	
	550V25A: PAAC XT rev3	01-JUN-07
Wafer Stage Long Stroke M X amp.	450V20A: PAAC AT-pepD	
	550V25A: PAAC XT rev3	01-JUN-07
Wafer Stage Long Stroke M Y1 amp.	450V20A: PAAC AT-pepD	
	550V25A: PAAC XT rev3	01-JUN-07
Wafer Stage Long Stroke M Y2 amp.	450V20A: PAAC AT-pepD	
	550V25A: PAAC XT rev3	01-JUN-07
Wafer Stage Measurement System	Agilent interferometers	07-APR-10
Wafer Stage Mirror Block Down Electronics	Absent	01-JUN-07
Wafer Stage Overlay Diagnostics	Disabled	22-MAY-16
Wafer Stage Short Stroke 1 XY1 amp.	PADC 100V/18A	
	PADC 130V/24A	01-JUN-07
Wafer Stage Short Stroke 1 XY2 amp.	PADC 100V/18A	
	PADC 130V/24A	01-JUN-07
Wafer Stage Short Stroke 1 XY3 amp.	PADC 100V/18A	
	PADC 130V/24A	01-JUN-07
Wafer Stage Short Stroke 1 Z1 amp.	PADC 100V/18A	
	PADC 52V/6A	01-JUN-07
Wafer Stage Short Stroke 1 Z2 amp.	PADC 100V/18A	
	PADC 52V/6A	01-JUN-07
Wafer Stage Short Stroke 1 Z3 amp.	PADC 100V/18A	
	PADC 52V/6A	01-JUN-07
Wafer Stage Short Stroke 2 XY1 amp.	PADC 100V/18A	
	PADC 130V/24A	01-JUN-07
Wafer Stage Short Stroke 2 XY2 amp.	PADC 100V/18A	
	PADC 130V/24A	01-JUN-07
Wafer Stage Short Stroke 2 XY3 amp.	PADC 100V/18A	

	PADC 130V/24A	01-JUN-07
Wafer Stage Short Stroke 2 Z1 amp.	PADC 100V/18A	
	PADC 52V/6A	01-JUN-07
Wafer Stage Short Stroke 2 Z2 amp.	PADC 100V/18A	
	PADC 52V/6A	01-JUN-07
Wafer Stage Short Stroke 2 Z3 amp.	PADC 100V/18A	
	PADC 52V/6A	01-JUN-07
Wafer Stage Type	Dual Chuck	01-JUN-07
Wafer Switch	Absent	01-JUN-07
Wafer Track	Present	26-OCT-12
Wafer stage technology	Wafer stage H-drive	07-APR-10
Wafer type used in the machine	300 mm - SEMI Notch	07-APR-10
Wafer z-map type.	Type 1: Pre-calculated setpoints from GLC	30-JAN-15
Wafer-Handler Air-Extraction presence	WH Air-Extraction hardware is absent	04-DEC-15
Wafers per Carrier	25	01-JUN-07
Warped wafer shape support	Disabled	13-FEB-20
Wavelength Adjustable	Adjustable	01-JUN-07
Weighing of 2-Sided X-interferometers	Variable interferometer weight factors	22-MAY-16
Wet Chuck Ex. while stay hovering (Chuck1=Exp,Chuck2=Mea)	Not Applicable	07-APR-10
Wet Chuck Ex. while stay hovering (Chuck1=Mea,Chuck2=Exp)	Not Applicable	07-APR-10
Wet Imaging Control Cabinet	Type B	
	Type C or Type D	25-OCT-12
Wet Imaging Control Rack	WICR-i4 or WICR-i5	19-SEP-11
Wet Vacuum unit version in EIM	No WVAC EIM unit installed	30-JAN-15
Wide Pellicle Detection	Absent	07-APR-10
Wide Pellicle Detection Type	DISABLED	30-JAN-15
XML Lot Report Content Level	Basic	07-APR-10
XML output for LITHOGUIDE	Disabled	01-JUN-07
XT Architecture Revision	Rev2	
	Rev3	01-JUN-07
XT REMA MPAC board type	MPAC type 1	07-APR-10

XT19x0 throughput performance enhancement package.	Not applicable	
	Standard performance settings	30-JAN-15
Z-capture on low reflectivity wafers	Z-capture on low reflectivity wafers is disabled.	14-DEC-10
ZERO Fiducial	ILIAS MK3	
	ILIAS MK4	01-JUN-07
Zeroing type for Encoders Measurement System	Using reference marks on the encoder scales	01-JUN-07
Zoom Axicon Architecture	ZZA	01-JUN-07
Zoom Axicon Type	170	
	190	01-JUN-07
board configuration	OADB	01-JUN-07
enables ihopc per image per chuck	disables ihopc per image per chuck	04-DEC-15
extended docking interface at Prealigner	ECC_OMM	01-JUN-07
mbds control	Present	01-JUN-07
purging configuration	purging CONFIG 3	
	purging CONFIG 8	25-OCT-12
routing for ASML test purposes	Disabled	19-JUN-07
switch for 3DOF / 6DOF HDM	HDM_TYPE_6DOF	07-APR-10
wildcard matching to reuse reticle heating TOPRC records	Reticle heating control calibration record reuse is disabled	04-DEC-15